

Notice of References Cited	Application/Control No. 10/728,070		Applicant(s)/Patent Under Reexamination CHOI ET AL.	
	Examiner Alvin T. Raetzsch		Art Unit 1754	Page 1 of 1

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
*	A	US-6,333,016	12-2001	Resasco et al.	423/447.3
*	B	US-2003/0181328 a1	09-2003	Hwang et al.	502/325
*	C	US-2003/0161782 a1	08-2003	Kim, Young-Nam	423/447.3
	D	US-			
	E	US-			
	F	US-			
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	T					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
*	U	Serp, P.; Kalck, P.; Feurer, R.; Chemical Vapor Deposition Methods for the Controlled Preparation of Supported Catalytic Materials, Chem. Rev. 2002, 102, 3085-3128.
	V	
	W	
	X	

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.